

ADJUSTABLE ELECTRODE ASSEMBLY FOR USE IN PROCESSING SUBSTRATES OF DIFFERING WIDTHS IN A PLASMA PROCESSING SYSTEM

Abstract of the Disclosure

An electrode assembly for use in a plasma processing system that includes removable rails that are adjustable for reconfiguring the electrode to accommodate substrates of different widths. The electrode assembly

5 includes an electrode having a plurality of first connecting members.

Associated with the electrode is a plurality of rails that cooperate for supporting the substrates on the electrode. Each of the rails includes a plurality of second connecting members. Each of the second connecting members is connected detachably with one of the first connecting members for removably mounting

10 the rails with the electrode.

FIG. 2



162162



G00002